

*IN THE UNITED STATES PATENT AND TRADEMARK OFFICE*

In re PATENT APPLICATION of :  
Ki-Hwan PARK et al. : Group Art Unit 1711  
Application No. 10/695,770 : Examiner F. Stinson  
Filed: October 30, 2003 : Confirmation No. 6935

METHOD OF AND APPARATUS FOR CLEANING SEMICONDUCTOR  
WAFERS

---

**AMENDMENT**

U.S. Patent and Trademark Office  
**E-FILING**  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

In response to the Office Action dated September 8, 2010, please amend the above-identified application according to the following:

**Amendments to the Specification** begins on page 2 of this paper.

**Amendments to the Claims** as reflected in the listing of claims which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 10 of this paper.